

Home Search List First Prev Go to Next Last Include

MicroPatent® PatSearch Fulltext: Record 1 of 1

Search scope: US Granted US Applications EP-A EP-B WO JP (bibliographic data only) DE-C,B DE-A DE-T DE-U GB-A FR-A
Years: 1991-2006
Patent/Publication No.: ((JP2004094203))

Order/Download Family Lookup Find Similar Legal Status
Go to first matching text

JP2004094203 A
CLEANING LIQUID FOR REMOVING
RESIST AND MANUFACTURING
METHOD FOR SEMICONDUCTOR
DEVICE
RENESAS TECHNOLOGY CORP
MATSUSHITA ELECTRIC IND CO
LTD EKC TECHNOLOGY KK

Abstract:

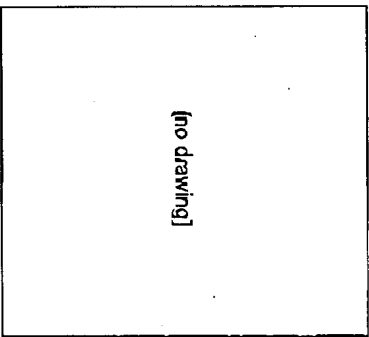
PROBLEM TO BE SOLVED: To

provide cleaning liquid for removing resist enhanced in a removing function of resist residual dross and resistance against corrosion of a copper film

and an insulator film, when the resist residual dross after etching or ashing, and other etching residual dross are removed in a semiconductor manufacturing process including a copper wiring process, and a manufacturing method for a semiconductor device using the cleaning liquid. SOLUTION: The cleaning liquid for removing the resist contains salt ((a) component) of hydrofluoric acid and base which does not contain metal, water-soluble organic solvent (b1 component), one or more acid (c component) selected from a group which is composed of organic acid and inorganic acid, and water (d component). Hydrogen ion concentration (pH) of the cleaning liquid is 4 to 8. Moreover, preferably, the cleaning liquid contains additionally ammonium salt (e1 component).

Inventor(s):

SUGANO ITARU
ASAOKA YASUHIRO
AZUMA MASAHIKO
HIDAKA YOSHIMARU
KISHIO ETSURO
AOYAMA TETSUO



SUZUKI TOMOKO
HIRAGA TOSHITAKA
NAGAI TOSHIHIKO

Application No. 2003174816 JP2003174816 JP, Filed 20030619, A1
Published 20040325

Original IPC(1-7): G03F00742
H01L021027 H01L021304

Priority:
JP 2002203987 20020712

Patents Citing This One No US, EP, or WO patent search reports have cited this patent.

Home Search List First Prev Go to Next Last

For further information, please contact:
Technical Support | Billing | Sales | General Information